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<b>To:</b> United States Patent and Trademark Office		<b>From:</b> Jonathan A. Hack
<b>Fax:</b> 703.872.9306	<b>Pages:</b> 11 (including cover sheet)	
<b>Phone:</b>	<b>Date:</b> December 20, 2004	
<b>Re:</b> U.S. Application No.: 10/085,753	<b>CC:</b>	
<input type="checkbox"/> <b>Urgent</b> <input type="checkbox"/> <b>For Review</b> <input type="checkbox"/> <b>Please Comment</b> <input type="checkbox"/> <b>Please Reply</b> <input type="checkbox"/> <b>Please Recycle</b>		

● **Comments:**

With respect to:

In Re the Application of: **TSUGA et al.**                          Group Art Unit: 1746  
U.S. Patent Application No.: 10/085,753                          Examiner: Michael Kornakov  
Filed: February 28, 2002                                  Attorney Docket No.: TI-31620  
Title: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

Please find:

1. Petition For Extension of Time
2. Amendment in response to the Office Action dated June 18, 2004

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**PATENT**

Attorney Docket No. TI-31620  
Application No.: 10/085,753  
Customer No.: 23494

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
TSUGA et al. ) Group Art Unit: 1746  
Application No.: 10/085,753 ) Examiner: Michael Kornakov  
Filed: February 28, 2002 )  
For: METHOD AND DEVICE FOR )  
REMOVING PARTICLES ON )  
SEMICONDUCTOR WAFERS )

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated June 18, 2004, the period for reply having been extended for three months, December 18 being a Saturday, by a request for extension of time filed concurrently herewith, please amend the application as follows:

**Amendments to the claims begin on page 2 of this paper.**

**Remarks begin on page 5 of this paper.**